Gas-Phase SN2 Reactions at Silicon and Carbon Centers. An Experimental Appraisal of Theory

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Abstract: The gas-phase kinetics of the reactions of H^- , D^- , OH^- , $\cdot C_2^-$, $\cdot C_4^-$, and C_4H^- with SiH₄ and the reactions of D^- , OH^- , $\cdot C_2^-$, $\cdot C_4^-$, and C_2H^- with CH₄ have been investigated at 297 ± 2 K using the flowing afterglow technique. The reactions with silane are characterized by a variety of channels and reaction efficiencies whereas methane was observed to be relatively unreactive. The rate constants measured for the reactions of H^- and D^- with SiH₄ and D with CH₄ are in accord with the energies of the reaction intermediates SiH₅⁻ and CH₅⁻ predicted by ab initio quantum mechanical calculations but do not corroborate the prediction of a reaction barrier for the attack of H⁻ on silane. This latter reaction, for which the SN2 channel is observed to compete with proton transfer, proceeds rapidly at 297 K.

The intrinsic energy surfaces of bimolecular nucleophilic substitution (SN2) reactions, which have been studied extensively in a variety of solvents, have recently become the subject of a number of ab initio and semiempirical molecular orbital calculations.²⁻¹⁰ Although calculations have been reported which also explore the influence of solvent on the intrinsic energetics of such reactions.¹¹ computational difficulties have generally prevented the incorporation of solvent effects into such calculations so that their direct comparison with measurements made in solution have been of limited value. Fortunately, gas-phase techniques have now become available which allow the direct experimental investigation of SN2 reactions proceeding in the absence of solvent molecules, viz., in vacuo.¹²⁻¹⁵ It has, therefore, become possible to conduct measurements on several specific SN2 reactions which have been scrutinized through molecular orbital calculations, and, consequently, to compare directly theoretical predictions with experiment. So far the experimental measurements have been restricted to specific rates of reaction at room temperature. The extent of the comparisons with theory has therefore been limited but the comparisons have nevertheless proven to be valuable. For example, quantum mechanical studies by Dedieu and Veillard⁵ and by Bader, Duke, and Messer⁶ had predicted energy barriers of 3.8 and 22 kcal mol^{-1} , respectively, for the SN2 reactions

$$H^- + CH_3F \rightarrow CH_4 + F^- \tag{1}$$

and

$$CN^- + CH_3F \to CH_3CN + F^-$$
(2)

The rate constants for these reactions at 296 K were subsequently measured in a flowing afterglow.¹⁴ When considered in the context of the traditional Arrhenius model, albeit somewhat over-simplified, the experimental values for the rate constants were consistent with activation energies of 3.6 and $\gtrsim 5$ kcal mol⁻¹, respectively, in good agreement with the theoretical predictions. These results provided, for the first time, a direct experimental measure of confidence for these quantum mechanical studies.

In this paper we wish to report gas-phase measurements which provide an empirical test for recent theoretical studies of the athermal symmetric silyl and methyl cation transfer reactions

$$H^- + MH_4 \rightarrow MH_4 + H^- \tag{3}$$

where M = Si and C. The energy surfaces of both reactions have been explored in a number of calculations. Recently Baybutt² has performed ab initio molecular orbital calculations in a comparative study of these two systems. He concludes that the carbon system should show a barrier to reaction since the reaction complex is of much higher energy (ca. +60 kcal mol⁻¹) than the reactants. unlike the silicon system for which the reaction complex is of lower energy (ca. -19 kcal mol⁻¹). Wilhite and Spialter⁴ have performed both semiempirical CNDO and ab initio calculations for a number of points along the H⁻ + SiH₄ reaction coordinate (approach of the hydride ion to a *face* of the tetrahedron of silane). They found that, whereas the CNDO calculation did not indicate a barrier to reaction. further ab initio calculations along the CNDO path predicted a barrier of 8.6 kcal mol⁻¹. The reaction complex SiH₅⁻ (a trigonal-bipyramidal form) was again found to be stable (by 16.9 kcal mol⁻¹) with respect to silane and the hydride ion.

The reactions of other nucleophiles (including several radical anions) with SiH_4 and CH_4 have also been explored in the present study. in part to provide further experimental observations with which future calculations can perhaps be compared.

Experimental Section

The experiments were performed using a flowing afterglow apparatus which has been described previously in detail.¹⁶ Briefly, helium or hydrogen is flowed down a 1.4 m, 8.9 cm diameter stainless steel tube at a velocity of $\sim 10^4$ cm s⁻¹ and at a pressure of ~ 0.3 Torr. A plasma containing the reactant ion of interest is generated at one end of the tube by electron impact on an appropriate neutral gas and sampled at the other end by a small on-axis leak coupled to a quadrupole mass spectrometer. The decline of the initial ion signal as seen by the mass spectrometer as a function of neutral reactant addition upstream of the sampling orifice affords a measure of the rate constant. The method of data analysis has also been discussed previously in considerable detail.¹⁶

In the present experiments $CH_4(CD_4)$ and C_2H_2 were bombarded with energetic electrons (40-60 eV) to produce the anions of interest. Under typical operating conditions the addition of CH_4 produced (in order of decreasing abundance) C_2H^- , $\cdot C_2^-$, $\cdot C^-$, and H^- while the addition of CD_4 resulted in the corresponding deuterated species. The addition of C_2H_2 produced (in order of decreasing abundance) C_2H^- , $\cdot C_2^-$, C_4H^- , $\cdot C_4^-$, and $\cdot C^-$.

The ions produced in the electron-impact region spend several milliseconds in the flowing plasma and undergo several thousand collisions with the buffer gas before they enter the reaction region. Consequently we believe that the anionic species involved in reaction have internal and translational energy distributions which are Maxwell-Boltzmann and are characterized by the temperature of the flowing plasma which is determined by the temperature of the stainless steel flow tube. The neutral reagent is added already in thermal equilibrium with the wall. The wall temperature is taken to be equal to the room temperature of 297 \pm 2 K.

Table I. Rate Constants and Product Channels for Reactions of Anions with SiH $_{\star}$ at 297 \pm 2 K

| Reaction | k _{exptl} ^a | kc ^b |
|---|---------------------------------|-----------------|
| $H^- + SiH_4 \rightarrow SiH_3^- + H_2$ | 0,57 ± 0.05 (3) | 4.95 |
| $D^{-} + SiH_4 \rightarrow SiH_3D + H$ $\rightarrow SiH_2D^{-} + H_2$ $\rightarrow SiH_3^{-} + HD$ | 2.2 ± 0.5 (4) | 3.56 |
| $OH^- + SiH_4 \rightarrow SiH_3^- + H_2O_4 \rightarrow SiH_0^- + H_1^-$ | 1.3 ± 0.2 (3) | 1.46 |
| $\cdot C^{-} + SiH_{4} \rightarrow SiH_{3}^{-} + \cdot CH$ | 0.062 ± 0.005 (5) | 1.65 |
| $ \begin{array}{c} \cdot C_2^{-} + \operatorname{SiH}_4 \to C_2 \operatorname{SiH}_3^{-} + \cdot H \\ \to (\operatorname{SiH}_3^{-} + \cdot C_2 \operatorname{H}) \end{array} \right] $ | 0.37 ± 0.02 (4) | 1.32 |
| $C_4^- + SiH_4 \rightarrow C_4SiH_3^- + H^-$ $\rightarrow (SiH_3^- + C_4H)$ | 0.084 ± 0.010 (3) | 1.11 |
| $C_2H^- + SiH_4 \rightarrow$ | ≲0.006 | 1.30 |
| $C_4H^- + SiH_4 \rightarrow$ | <0.005 | 1.11 |
| $Cl^- + SiH_4 \rightarrow$ | $\widetilde{\lesssim}$ 0.002 | 1.19 |
| $NO_2^- + SiH_4 \rightarrow$ | ≲0.003 | 1.12 |

^{*a*} The mean value of the experimentally determined rate constant in units of 10^{-9} cm³ molecule⁻¹ s⁻¹. The limits given along with the mean value represent the precision of the measurements. The number of measurements is given in parentheses. ^{*b*} The calculated collision rate constant in units of 10^{-9} cm³ molecule⁻¹ s⁻¹ according to the Langevin theory, ref 17, with α (SiH₄) = 4.34 Å³, ref 18.

Table II. Rate Constants for Reactions of Anions with CH_4 at 297 \pm 2 K

^{*a*}Experimentally determined upper limits to the rate constants in units of 10⁻⁹ cm³ molecule⁻¹ s⁻¹. ^{*b*} The calculated collision rate constant in units of 10⁻⁹ cm³ molecule⁻¹ s⁻¹ according to the Langevin theory, ref 17. with $\alpha(CH_4) = 2.56$ Å³, ref 19. $\alpha(CD_4)$ is taken to be equal to $\alpha(CH_4)$. ^{*c*} Previous flowing afterglow results, ref 20. ^{*d*} Previous flowing afterglow results, ref 21.

The following gases were used: helium (Linde, Prepurified Grade, 99.995% He), hydrogen (Linde, 99.95% H₂), methane (Matheson Ultra High Purity, 99.97% CH₄), acetylene (Matheson, Purified Grade, 99.6% C_2H_2), CD₄ (Merck Sharp and Dohme, 99 atom % D), and SiH₄ (Matheson, Semiconductor Grade, 99.95% SiH₄).

Results

The rate constant measurements are summarized in Tables I and II. The best estimate of a true value is taken to be the mean of a series of measurements. The limits given along with the mean value throughout this section represent the best estimate of the precision.²² Sources of error have been described previously.¹⁶ The absolute accuracy of the reported rate constants is estimated to be $\pm 20\%$.

 $H^- + SiH_4$. H^- was observed to react with SiH₄ upon the addition of the latter into a flowing CH₄-He plasma in which H⁻ was initially a dominant negative ion. Figure 1 is representative of the observations made in three experiments in which the effective reaction length. L. was fixed at 60 cm. the gas velocity. $\bar{\nu}$, had values from 8.3 to 8.5 × 10³ cm s⁻¹. and the total gas pressure was in the range 0.385-0.424 Torr. The OH⁻ initially present in the reaction region can be attributed to trace amounts of H₂O impurities in the flowing plasma. The disappearance of H⁻ was accompanied by the production of SiH₃⁻ which is indicative of the occurrence of the proton-transfer reaction



Figure 1. The variation of negative ion signals recorded upon the addition of SiH₄ into a flowing CH₄-He plasma: T = 296 K, P = 0.424 Torr. CH₄ flow = 9.5×10^{17} molecules s⁻¹, L = 60 cm, and $\bar{v} = 8.3 \times 10^{3}$ cm s⁻¹.

The production of SiH₃O⁻ must be attributed to the reaction of OH⁻ with SiH₄ which was investigated independently in separate experiments which will be described later in this section. The three measurements of the H⁻ decay provided a value for $k_{4b} = (5.7 \pm 0.5) \times 10^{-10}$ cm³ molecule⁻¹ s⁻¹. The identification of the displacement channel

$$H^- + SiH_4 \rightarrow SiH_4 + H^- \tag{4a}$$

was precluded in these experiments since the mass spectrometer could not distinguish between reactant and product H^- ions. Attempts were therefore made to observe this channel using the isotopic species. D^- , as the nucleophile.

 $D^- + SiH_4$. D^- was generated from CD_4 introduced into the helium buffer gas upstream from the electron gun and. as shown in Figure 2. was observed to react rapidly with SiH₄ added downstream. Figure 2 includes the increase of the stoichiometrically allowed product ion signals which were observed to accompany the D^- signal decay and also shows the presence and reaction of other major negative ions. viz., OH⁻ and C₂D⁻. Not shown are the ions OD⁻. \cdot C₂⁻, and \cdot C⁻ which were also observed to be present and to react with SiH₄.

The production of H^- can be ascribed solely to the reaction of D^- with SiH_4 since separate experiments conducted in the absence of D^- and to be described in the next two sections indicated that the hydride ion is not a product of the reaction of OH^- , $\cdot C^-$, $\cdot C_2^-$, or C_2H^- with SiH_4 . Furthermore, the magnitude of the increase in the H^- signal indicates that H^- displacement is the main channel of the reaction of D^- with SiH_4 :

$$D^- + SiH_4 \rightarrow SiH_3D + H^-$$
(5a)

We estimate that this channel is preferred by at least 4 to 1 over the channels:

$$D^- + SiH_4 \rightarrow SiH_3^- + HD \tag{5b}$$

$$D^- + SiH_4 \rightarrow SiH_2D^- + H_2 \tag{5c}$$

The reactions of the other aforementioned negative ions present in the flowing plasma as well as mass discrimination in the mass spectrometer sampling and detection system



Figure 2. The variation of negative ion signals recorded upon addition of SiH₄ into a flowing CD₄-He plasma. Not shown are the ions OD⁻, C₂⁻, and C⁻ which were also observed to react with SiH₄. The slope of the D⁻ decay provides a rate constant of 2.21 × 10⁻⁹ cm³ molecule⁻¹ s⁻¹: T = 295 K, P = 0.298 Torr. CD₄ flow = 3.06 × 10¹⁸ molecules s⁻¹. L = 60 cm, and $v = 8.4 \times 10^3$ cm s⁻¹. The production of ²⁸SiH₂D⁻ (dashed curve) is determined from the production of n/e 32 by subtracting the contribution to m/e 32 by the isotopic ion ²⁹SiH₃⁻.

prevented an unequivocal assignment of the actual branching ratio of channels 5a, 5b, and 5c. Four measurements of the D⁻ decay provided a value for $k_5 = (2.2 \pm 0.5) \times 10^{-9}$ cm³ molecule⁻¹ s⁻¹ at L = 60 cm. v = 7.9 to 8.4×10^3 cm s⁻¹, and P = 0.268-0.353 Torr.

 $OH^- + SiH_4$. In order to determine the specific rate and product channels for the reaction of OH^- with SiH₄. the latter was added into a H₂O-He plasma in which OH^- and O^- were initially dominant negative ions. Both OH^- and O^- were observed to react rapidly with SiH₄ to produce SiH₃⁻ and SiH₃O⁻. In order to elucidate the branching ratio of the OH⁻ reaction the experiment was repeated in a hydrogen buffer in which complications due to the \cdotO^- reaction could be avoided since \cdotO^- reacts rapidly with H₂ by associative detachment. viz.

$$\cdot O^- + H_2 \rightarrow H_2 O + e \tag{6}$$

The results of an experiment conducted with a hydrogen buffer are shown in Figure 3. The two product channels observed were:

$$OH^- + SiH_4 \rightarrow SiH_3^- + H_2O$$
(7a)

$$OH^- + SiH_4 \rightarrow SiH_3O^- + H_2 \tag{7b}$$

Proton transfer is the preferred channel by about 2:1. The displacement reaction:

$$OH^- + SiH_4 \rightarrow SiH_3OH + H^-$$
(7c)

would be difficult to observe under these operating conditions since H⁻ reacts rapidly with H₂O to produce OH⁻. However, in a separate experiment (in pure He) in which OH⁻ was present as an impurity ion and H₂O was essentially absent, the addition of SiH₄ did not give rise to H⁻. We, therefore, conclude that channel 7c can only be a minor channel in the reaction of OH⁻ with SiH₄.

Three experiments (two in He at 0.319 and 0.504 Torr and one in H₂ at 0.277 Torr) yielded a value for k_7 of (1.3 \pm 0.2) \times 10⁻⁹ cm³ molecule⁻¹ s⁻¹. The reaction length was fixed at 60 cm and \bar{v} had values in the range 7.7 to 8.6 \times 10³ cm s⁻¹.



Figure 3. Variation of negative ion signals recorded upon addition of SiH₄ into a flowing H₂O-H₂ plasma. The slope of the OH⁻ decay yields a rate constant of 1.38×10^{-9} cm³ molecule⁻¹ s⁻¹. SiH₃⁻² and SiH₃O⁻ were the only product ions observed: T = 297 K, P = 0.277 Torr, H₂O flow ~10¹⁷ molecules s⁻¹, L = 60 cm, and $\bar{\nu} = 7.7 \times 10^3$ cm s⁻¹.

 $C_xH_y^- + SiH_4$. The reactions of carbonaceous anions with SiH₄ were explored further by adding SiH₄ into a flowing C₂H₂-He plasma. Figure 4 shows the observed variations of negative ion signals. The slope of the decay of each anion provides a measure of the rate constant for the reaction of that anion with SiH₄. Five experiments were performed in which one or more of the anions $\cdot C^-$. $\cdot C_2^-$. C_2H^- . $\cdot C_4^-$. and C_4H^- were monitored as a function of SiH₄ addition. The rate constants determined for their reactions with SiH₄ are included in Table I. The impurity ions Cl⁻ and NO₂⁻ were observed not to react. In these five experiments the C₂H₂ flow had values in the range 5.97 × 10^{17} to 2.32 × 10^{18} molecules s⁻¹. *P* was in the range 0.304-0.370 Torr. $\bar{\nu}$ in the range 7.9 to 8.3 × 10^3 cm s⁻¹. and the reaction length. *L*. had values of 59 and 85 cm.

The nature of the product ion spectrum and its variation with SiH_4 addition suggest that $\cdot C^-$ reacts with SiH_4 mainly by proton transfer according to:

$$\cdot C^{-} + \mathrm{SiH}_4 \to \mathrm{SiH}_3^{-} + \cdot \mathrm{CH}$$
(8)

and that $\cdot C_2^-$ and $\cdot C_4^-$ react at least in part by H-atom displacement according to:

$$C_2^- + \mathrm{SiH}_4 \to -C_2 \mathrm{SiH}_3 + \cdot \mathrm{H} \tag{9}$$

$$\cdot C_4^- + \mathrm{SiH}_4 \to -C_4 \mathrm{SiH}_3 + \cdot \mathrm{H}$$
(10)

There was no evidence for the formation of $-CSiH_3$ through H-atom displacement by $\cdot C^-$. Also some of the SiH₃⁻ ions appear to be produced by slow proton transfer reactions of C₂H⁻ and/or C₄H⁻ with SiH₄. There was no evidence for the occurrence of H⁻ displacement which, for the adopted experimental conditions, would be reflected by an initial increase in the C₂H⁻ signal since any H⁻ produced would react rapidly by proton transfer with the C₂H₂ present in the flowing plasma. The observation of H⁻ was, however, rendered difficult by the large initial C₂H⁻ signal.

 $D^- + CH_4$. As was the case for reaction 4a, the identification of the displacement channel

$$H^- + CH_4 \rightarrow CH_4 + H^- \tag{11}$$

was prevented in these experiments by the inability of the



Figure 4. A comparison of the rates of reaction of various carbonaceous anions with SiH₄ which is added to a flowing C₂H₂-He plasma. The slope of the C⁻ decay corresponds to a rate constant $k = 5.4 \times 10^{-11}$ cm³ molecule⁻¹ s⁻¹: T = 298 K, P = 0.304 Torr. C₂H₂ flow = 6.0×10^{17} molecules s⁻¹, L = 60 cm, and $b = 7.9 \times 10^3$ cm s⁻¹. The identification of C₄SiH₃⁻¹ was not unequivocal since this product ion could only be observed at low resolution. The identification is uncertain to the extent of the number of H atoms in C₄SiH₃⁻¹ where x = 0-4.

mass spectrometer to distinguish between reactant and product H^- ions so that the analogous reaction involving D^- , viz..

$$D^- + CH_4 \rightarrow CH_3D + H^-$$
(12)

was investigated instead. CH₄ was added into a flowing CD₄-He plasma containing D⁻. The results of such an experiment are shown in Figure 5. The D⁻ ions are not depleted nor are H⁻ ions produced as the CH₄ is added. These results provide an upper limit for k_{12} of 10^{-13} cm³ molecule⁻¹ s⁻¹.

 $H^- + CD_4$. In the studies of the reaction of D^- with SiH₄. the D^- ions were produced from CD_4 which was added upstream of the electron gun and was therefore also present in the reaction region. The H⁻ produced by reaction 5a therefore could have reacted with CD₄ by displacement according to:

$$H^- + CD_4 \rightarrow CD_3H + D^-$$
(13)

At the CD₄ flows used in these experiments ($\sim 2 \times 10^{18}$ molecules s⁻¹) the rapid occurrence of reaction 13 would have been manifested by the appearance of appreciable curvature in the D⁻ decay. No such curvature is evident in Figure 2. From this qualitative observation we estimate that $k_{13} \leq 1 \times 10^{-12}$ cm³ molecule⁻¹ s⁻¹.

Discussion

and

The reactions of anions with SiH₄ and CH₄ have not been studied extensively by experiment in the past. Brauman and co-workers²³ have reported the observation of the proton transfer reactions:

$$OH^- + SiH_4 \rightarrow SiH_3^- + H_2O \tag{7a}$$

4)

$$NH_2^- + SiH_4 \rightarrow SiH_3^- + NH_3 \qquad (1)$$

For both of these reactions their ion-cyclotron-resonance measurements implied a preferred direction for proton transfer as indicated. There was apparently no evidence for the occurrence of a displacement leading to the formation



Figure 5. A study of the displacement of H⁻ in CH₄ by D⁻. Methane is added to a flowing CD₄-He plasma: T = 298 K, P = 0.359 Torr, CD₄ flow = 1.39×10^{18} molecules s⁻¹, L = 85 cm, and $v = 8.1 \times 10^3$ cm s⁻¹.

of H⁻. Brauman and co-workers also did not report the observation of channel 7b nor did they measure rate constants for reactions 7a and 14. The reactions of OH⁻. ·C⁻. ·C₂⁻. and C₂H⁻ with CH₄ have been investigated previously²¹ with the flowing afterglow technique which allowed the determination of the upper limits to the total specific rates of reaction of these anions with CH₄ which are indicated in Table II.

Comparisons with Theoretical Predictions. The ab initio quantum mechanical calculations for reactions of anions with SiH₄ and CH₄ have been restricted to hydride ion attack. They have been concerned principally with the evolution of the geometry, energy, and electronic structure of the reacting species in their formation of the intermediates SiH_5^- and CH_5^- , viz., along the reaction paths:

$$H^- + SiH_4 \rightarrow SiH_5^- \tag{15}$$

$$H^- + CH_4 \to CH_5^- \tag{16}$$

The observations reported here for the H^- and D^- reactions allow an experimental assessment of the energies of the intermediates or the energy barriers along the reaction paths predicted by these calculations.

The calculations of Wilhite and Spialter⁴ predict that the gas-phase reaction (eq 15) proceeds via attack of the hydride ion on a face of the tetrahedron of silane with an energy barrier of 8.6 kcal mol⁻¹ yielding a trigonal bipyramidal form of SiH5⁻ that is 16.93 kcal mol⁻¹ stable with respect to the separated reactants. The energy difference is calculated to be -18.6 kcal mol⁻¹ by Baybutt.² Our experimental results are in accord with a lower energy for the SiH₅⁻ intermediate but do not corroborate the prediction of a large reaction barrier for the H⁻ attack. A comparison of k_5 determined in this study with the capture rate constant which can be calculated from the classical Langevin theory of ion molecule collisions¹⁷ indicates that at least six out of ten collisions of D⁻ with SiH₄ lead to reaction.²⁴ Thus it appears that reaction 15 proceeds with little or no activation energy.²⁵ The magnitude of this activation energy. E_a , can be estimated²⁷ in the traditional Arrhenius manner according to

$$k_{\text{exptl}} = k_{\text{c}} e^{-E_{\text{a}}/RT} \tag{17}$$

where k_{exptl} is the measured and k_c is the capture rate constant.²¹ Equation 17 yields a value for $E_a \simeq 0.3$ kcal mol⁻¹ which, as a result of the oversimplification introduced by eq 17, must be regarded as an upper limit.²¹ An activation energy of 8.6 kcal mol⁻¹ would result in a value for $k_5 \sim 2 \times 10^{-15}$ cm³ molecule⁻¹ s⁻¹. The discrepancy between theory and experiment for the activation energy of reaction 15 probably reflects a deficiency in the theory—either a lack of proper polarizing functions (the ab initio calculations by Wilhite and Spialter⁴ did not include p-type basis functions on the hydrogens) or perhaps an incorrect approach geometry.

The many calculations^{2,4,5,7-10} of portions of the potential energy surface of reaction 16 all predict a much higher energy for the reaction intermediate CH_5^- than the separated reactants $H^- + CH_4$. For example, Dedieu and Veillard⁵ calculated a difference of 60.2 kcal mol⁻¹. This result is in complete accord with our room temperature measurements of eq 12 and 13 which indicate an activation energy which may be at least as large as 6 kcal mol⁻¹.

Competition between Product Channels. The quantum mechanical calculations reported for reactions of anions with SiH₄ and CH₄ have as yet not been extended to include product channels other than H⁻ displacement. However, the observations reported in this study for the reactions of anions with SiH₄ demonstrate that H⁻ displacement often proceeds in competition with alternate product channels. The channels observed with the nucleophiles X⁻ = H⁻, D⁻, OH⁻, ·C⁻, ·C₂⁻, and ·C₄⁻ include hydride ion displacement (18a). hydrogen atom displacement (18b), proton transfer (18c), and hydrogen elimination (18d):

$$X^- + SiH_4 \rightarrow XSiH_3 + H^-$$
(18a)

$$X^{-} + SiH_4 \rightarrow -XSiH_3 + H$$
 (18b)

$$X^- + SiH_4 \rightarrow SiH_3^- + HX$$
 (18c)

$$X^- + SiH_4 \rightarrow -XSiH_2 + H_2$$
 (18d)

For most of the nucleophiles investigated at least two of these four channels were observed to be competing with each other. For example, although D^- reacted with SiH₄ predominantly by H⁻ displacement, a portion of the reactive collisions resulted in the transfer of a proton. For the reaction of OH⁻ with SiH₄, competition was observed between channels 18c and 18d.

The H^- displacement channel is often excluded on thermodynamic grounds. For this channel to be exothermic, the following condition must be satisfied:

$$D(\text{SiH}_3-\text{X}) > D(\text{SiH}_3-\text{H}) + \text{EA}(\text{X}) - \text{EA}(\text{H}) >$$

63 kcal mol⁻¹ + EA(X)

where the bond dissociation energy $D(\text{SiH}_3\text{-H}) = 80$ kcal mol^{-1} and EA(H) = 17.4 kcal $\text{mol}^{-1} 28.29$ The electron affinities of the species X used in this study are generally at least 25 kcal mol^{-1} and as large as 83 kcal mol^{-1} . Although the values for $D(\text{SiH}_3\text{-X})$ are generally not known, they are unlikely to be large enough to compensate for this high electron affinity of X. The H⁻ displacement channel is therefore likely to be thermodynamically unfavorable and any reaction of the anion with SiH₄ will proceed via other channels as was observed to be the case for the reactions of OH⁻. \cdot C⁻. \cdot C⁻.

The reaction of $\cdot C^-$ with SiH₄ was observed to proceed only via proton transfer which may be exothermic by as much as ~4 kcal mol⁻¹ according to the recent determination of EA(SiH₃) $\leq 1.44 \pm 0.03 \text{ eV}$.³⁰ The reaction is, however, unusually slow as proton transfer in the gas phase generally proceeds on nearly every collision.³¹ In fact, this is one of the slowest exothermic proton transfer reactions observed to date. We suggest that the relative inefficiency of this reaction may be attributed to the violation of spin conservation which is involved:

$$\cdot C^{-}(quartet) + SiH_4(singlet) \rightarrow SiH_3^{-}(singlet) + \cdot CH(doublet)$$
 (8a)

Other exothermic proton transfer reactions involving $C^{-}({}^{4}S)$ have been observed to be slow³¹ and indeed are expected to be slow for the same reason. Our measurements also indicate that the proton transfer reactions:

$$C_2H^- + SiH_4 \rightarrow SiH_3^- + C_2H_2$$
 (19)

and

$$C_4H^- + SiH_4 \rightarrow SiH_3^- + C_4H_2$$
 (20)

proceed extremely slowly in spite of the fact that SiH_4 is a much stronger acid than C_2H_2 and probably also C_4H_2 . We cannot explain this result.

When the species X^- is a radical, then H atom displacement becomes a viable alternate channel since $XSiH_3$ is not likely to have a significant electron affinity. This is evidenced by the production of $-C_2SiH_3$ and $-C_4SiH_3$ observed in these experiments as a result of the reactions with SiH_4 of the radical anions $-C_2^-$ and $-C_4^-$, respectively. The carbon analogues, viz., $-C_3H_3$ and $-C_5H_3$, have been observed to be stable in the gas phase. H-Atom transfer is another channel which, although not observed in these experiments, should be considered when X^- is a radical. For example, the reaction

$$\cdot C_2^- + \operatorname{SiH}_4 \to C_2 H^- + \cdot \operatorname{SiH}_3 \tag{9b}$$

is exothermic by ~ 25 kcal mol⁻¹ and therefore thermodynamically favorable.

The nonreactivity of CH₄ towards anions, which is immediately evident from an inspection of Table II, contrasts the reactivity generally observed for SiH₄ towards the same anions. This striking difference in reactivity can, however, be rationalized simply in terms of the thermodynamics of these systems. A thermodynamic analysis of channels 18a to 18d for CH₄ indicates that all of these channels are in fact endothermic for $X^- = OH^-$, $\cdot C^-$, $\cdot C_2^-$, and C_2H^- so that they are not expected to proceed rapidly at the temperature of these experiments.

A number of associative detachment channels resulting in the "insertion" of $C_x H_y^-$ are thermodynamically accessible to the reactions of $\cdot C^-$. $\cdot C_2^-$, and $C_2 H^-$ with CH₄ at 300 K, for example:²¹

$$C^- + CH_4 \rightarrow C_2H_4 + e \tag{21}$$

$$C_2^- + CH_4 \rightarrow C_3H_4 + e \tag{22}$$

$$C_2H^- + CH_4 \rightarrow CH_2CHCH_2 + e$$
(23)

Analogous reactions are presumably also thermodynamically allowed in the case of SiH₄. However, in both cases, constraints introduced by the required breaking and making of bonds are likely to lead to activation energy barriers of sufficient magnitude to prevent their observation at room temperature.²¹

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Molecular Structure of 1,2-Bis(trifluoromethyl)dithiete by Vapor Phase Electron Diffraction

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Abstract: The molecular structure of 1,2-bis(trifluoromethyl)dithiete has been determined in the vapor phase by electron diffraction. The results confirm the dithiete structure, in which the principal geometrical parameters, based on C_2 symmetry, are: $r_g(C-F) = 1.326 \pm 0.003$, $r_g(C=C) = 1.40 \pm 0.03$, $r_g(C-C) = 1.50 \pm 0.01$, $r_g(S-C) = 1.73 \pm 0.01$, $r_g(S-S) = 2.05 \pm 0.01$ Å; $\angle (C=C-S) = 100.8 \pm 0.6$, $\angle (C=C-C) = 122.9 \pm 0.7$, $\angle (F-C-C) = 110.8 \pm 0.6^\circ$. The rotational parameter τ (S—C—C–S) = 0.4 ± 3.4° indicates no significant deviation from planarity in the C₂S₂ ring excluding shrinkage effects which were not included in the analysis. The CF₃ groups are semistaggered, rotated about the C-C bonds by $34 \pm$ 6° relative to planar trans F-C-C=C. The quoted uncertainties represent the estimated limits of experimental errors. A comparison with other structures suggests delocalization of the carbon-carbon π system to include the sulfur atoms, but without appreciable participation of the S-S bond.

1.2-Bis(trifluoromethyl)dithiete was the first compound synthesized in which the unusual dithiete ring¹ could be postulated. Infrared and ¹⁹F NMR spectra² revealed the presence of a C=C bond, and showed that the CF_3 groups are attached to a doubly bonded carbon atom, but the red color of the compound prevented any observation of the sulfur-sulfur vibrations by Raman spectroscopy. Simple molecular orbital calculations³ showed that structure (I). involving a dithiete ring, is more stable than the acyclic dithione structure (II).



The title compound has been extensively used in the preparation of dithiolene complexes of a number of transition and main group metals.⁴ It is apparent that in all of these complexes, ring opening allows the 1.2-bis(trifluoromethyl)dithiete to act as a bidentate ligand, and a number of x-ray crystallographic structure studies of compounds with transition metal ions have been reported (see below). We have now determined the structure of the parent compound in the vapor phase by electron diffraction. and find that I is indeed the correct formulation under these experimental conditions.

Experimental Section

A sample of 1,2-bis(trifluoromethyl)dithiete, kindly provided by Dr. A. T. Berniaz of Simon Fraser University, showed no impurity bands in its infrared spectrum and was used without further purification.

Sectored electron diffraction patterns were recorded on the University of Windsor apparatus⁵ on Kodak 4×5 in. electron image plates. The experimental conditions for the dithiete exposures are presented in Table I. In each experiment, separate CS₂ patterns were recorded for the s scale calibration using the standard CS_2 structural parameters reported by Kuchitsu⁶ ($s = (4\pi/\lambda) \sin(\theta/\lambda)$ 2): λ = electron wavelength: θ (diffraction angle) = tan⁻¹ (r/L) where r is the radius and L is the camera length).

The optical densities of the experimental plates were sampled at 0.1095 mm intervals with the microdensitometer⁵ described previously, with the plate spinning and moving continuously so that an annular portion. 0.075 mm, of the plate was sampled in each of 350 measurements obtained for the radial range 0.75 < r < 4.5cm. Interpolation of densities at $\pi/10$ intervals in s (by the Lagrange method) was based on six points for long camera plates, and three points for short camera plates. The interpolated optical densites were converted to relative intensities by the correction⁷